

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **RALPH KURT, MICHAEL CORNELIS VAN BEEK,
ANTONIE ELLERT DUISTERWINKEL,
ERIK RENE KIEFT,
HANS MEILING,
BASTIAAN MATTHIAS MERTENS,
JOHANNES HUBERTUS JOSEPHINA MOORS,
LUCAS HENRICUS JOHANNES STEVENS, and
BASTIAAN THEODOOR WOLSCHRIJN**

Application No.:	TO BE ASSIGNED	Confirmation No:
Filed:	February 23, 2004	Group No.:
		Examiner
For:	METHOD AND DEVICE FOR MEASURING CONTAMINATION OF A SURFACE OF A COMPONENT OF A LITHOGRAPHIC APPARATUS	

**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

**APPLICATION DATA SHEET
37 C.F.R. § 1.76**

BIBLIOGRAPHIC DATA

1. Applicant information

First applicant: **RALPH KURT**
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2. Correspondence information

Correspondence for this application should be addressed as follows:

Customer No.: 00909

3. Application information

Title of Invention: **METHOD AND DEVICE FOR MEASURING CONTAMINATION
OF A SURFACE OF A COMPONENT OF A LITHOGRAPHIC APPARATUS**

Docket number assigned to this application: 081468-0308336

Suggested Classification: Class:

Subclass:

Technology Center to which subject matter is assigned:

Total number of drawing sheets: 6

Type of application: Utility

Application is to be published. Suggested drawing figure for publication: FIGURE 2

Secrecy order under § 5.2:

This application does not disclose subject matter of an application which is under a secrecy order pursuant to § 5.2.

4. Representative information

The following have a power of attorney or authorization of agent in this application:

Customer No.: 00909

5. Foreign priority information

Foreign priority is claimed for this application as follows:

Country: EUROPE
Application No.: 03075548.2
Filing Date: February 24, 2003

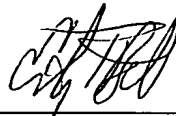
6. Assignee information

The assignee(s) of this application is/are:

ASML NETHERLANDS B.V.
De Run 6501, NL-5504 DR Veldhoven, The Netherlands
Extent of interest of assignee in application: ENTIRE RIGHT, TITLE AND INTEREST

Date: February 23, 2004

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